Ultra High Vacuum MBE & Evaporation systems
- Limit pressure : 5.10⁻¹⁰ mbar
- Up to 5 evaporation cells
- Electron source
- Substrate holder manipulator
- Load lock chamber

Sputtering system
- Limit pressure : 5.10⁻⁶ mbar
- Up to 6 magnetron cathodes RF and DC
- Electron source
- Substrate holder manipulator
- Load lock chamber and storage manipulator

Laser Ablation system
- Limit pressure : 10⁻¹⁰ mbar
- Motorised target holder manipulator
- Substrate holder manipulator
- Load lock chamber

Analysis system XPS, AES, ISS, LEIS
- Limit pressure : 10⁻¹⁰ mbar
- High resolution analyser
- R-X monochromator
- Focused ion source
- Load lock chamber and storage manipulator

Transfer tube UHV : Mecatrans
- Limit pressure : 10⁻¹⁰ mbar
- Transmission of movements with magnetic coupling
- Illimited length

- 25 years’ experience in thin film deposition systems design
- On demand deposition and analysis systems according to customer’s specifications
- Integration of high-performance components
- Achievements for the most Research laboratories: CNRS, CEA, Universities, St. Gobain, Thales, ST Microelectronics ......
Direct drive (PTD) and micrometer (PTV) feedthroughs
- Flanges CF16 or CF40
- Run 25, 50 or 100 mm

Rotation motion feedthroughs (TMR)
- Flanges CF16 or CF40
- Manual or pneumatic actuation
- With or without hollow shaft
- Options: reinforced axis, graduation, motorisation

Translators RLTM and MTZ
- Run 50 to 200 mm
- Flanges 40CF to 200CF
- Manual or motorised actuation

3 axis manipulators MT3 et MTS3
- Run Z from 50 to 200 mm
- Run X and Y ±12 mm or ±17.5 mm
- Flanges 63CF to 200CF
- Manual or motorised actuation

Transfer rods
- Magnetic rods
  - CF40 flanges
  - Run 600, 800 and 1000 mm
- Mechanical rods
  - CF40 or CF63 flanges
  - Run 600, 800 and 1000 mm
  - Special run on request

Electrical feedthroughs
- 16CF or CF40 flanges
- Current from 5A to 800 A
- Voltage from 500 V to 15 kV
- DC or RF
- Single / Multi-connector, SubD, BNC

Thermocouple feedthroughs
- Thermocouples type K or C
- 1 or 2 pairs
- Combined thermocouple and electrical feedthroughs

Liquid feedthroughs
- CF16 or CF40 flanges
- 1 or 2 connectors

All flanges and connectors are made of non-magnetic stainless steel 316L bakeable at 400°C
We offer a wide range of components:
- CF, ISO, KF flanges
- Copper, Viton gaskets
- Straight, tee, elbow, flexible connectors, cubes...
- 4 and 6 way cross
- Adaptors
- Viewports
- Viewport shutters
- Fast opening viewport
MECA 2000, specialist in vacuum and Ultra High Vacuum technologies for more than 25 years, is a division of Vinci Technologies since early 2008.

We are based in Nanterre (92), near Paris, in new offices including a clean room and all the equipment necessary to achieve UHV systems (leak detection, cleaning ultrasounds, etc ...)

With a long experience in the sector, Meca 2000 gives centrality to the quality of its systems. Technicians and engineers are highly qualified and experienced.

High quality guarantees:

- Design department equipped with Solidworks
- All the chambers are manufactured strictly with the techniques of UHV technologies
- The welds are tested with Helium
- A chemical cleaning according to protocols specific to the UHV approved by the CEA and the ESRF
- Ovens for baking up to 400°C. We conduct more tests and trials within each stage of manufacture to verify the compliance of the system and compliance with your specifications

VINCI TECHNOLOGIES
DIVISION MECA 2000

27 B Rue du Port – 92022 NANTERRE - FRANCE
Tel : +33 1.41.37.92.20 / Fax : +33 1.41.37.04.76

E-mail : meca2000@vinci-technologies.com